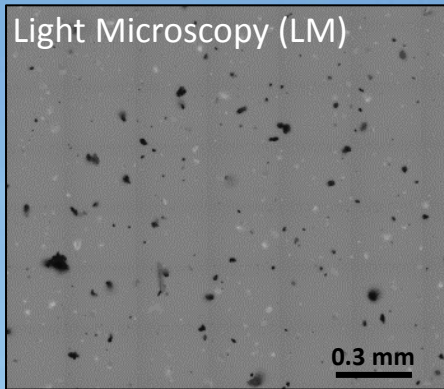
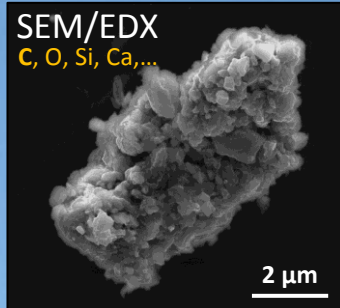


Light Microscopy (LM)



SEM/EDX
C, O, Si, Ca,...



Flexible dust monitoring with the Sigma-2 passive sampler

Sampling / Analysis

- Passive sampling after the VDI guideline 2119:2013 for LM, SEM/EDX and ICP-MS
- Suitable for particles with a geometric diameter of 2.5 – 80 μm
- Quantitative light microscopy analysis
- Morpho-chemical particle characterization based on SEM/EDX* analysis

* SEM/EDX = Scanning Electron Microscopy coupled to energy dispersive x-ray spectroscopy

Output/results

- Grain size distribution of dust
- Grain size dependent mass and particle number concentrations
- Mean values of 1-4 weeks intervals
- Differentiation of anthropogenic and natural dust fractions
- Quantitative morphological parameters and elemental composition for each single particle
- Determination of particle sources

Ideal for electricity independent...

... and low cost measurements of particulate matter in case of complaints (determination of particle source, toxicity etc.)

... approximate PM₁₀ measurements

... and low cost QA of continuous analysers (TEOM, Betameter, optical particle counter etc...)

... optimal combination of high-resolution measurements timewise (FIDAS200) and compositionally (SEM/EDX)

... validation of spatially high-resolution PM₁₀ modelling

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